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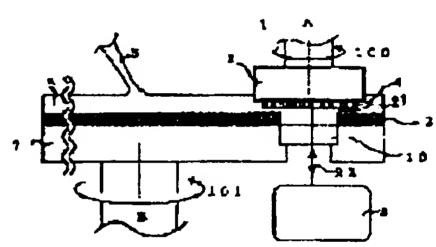
MIYAJI AKIRA

(54) POLISHING DEVICE

(57) Abstract:

PROBLEM TO BE SOLVED: To reduce the reflection light on the boundary surface between a detection window and abrasive liquid by providing a grinding body with at least one detection window for penetrating the measurement light and the signal light for measuring the grinding condition during the grinding.

SOLUTION: A grinding head 3 is rotated (100) on a shaft A by a proper means, and a surface plate 7 is rotated (101) on a shaft B by a proper means. During this process, a surface to be ground of a wafer 4 is ground by the action of the abrasive liquid 6 and a grinding pad 2. During the grinding, the measurement light emitted from a final point detecting device 8 penetrates through a detection window 10, penetrates through the abrasive liquid, and reaches the surface to be ground of the wafer 4, and the reflection light having the information on the surface to be ground penetrates through the abrasive liquid and the detection window 10 again as the signal light, and is detected by an optical detecting device of the final point detecting device 8. On this occasion, the detection window 10 is formed by a glass plate. The refraction factor of this glass plate is determined to be approximately same as that of the abrasive liquid.



LEGAL STATUS

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